

SEMICONDUCTOR CHAMBER

ABSTRACT

5 The present disclosure provides a semiconductor chamber, including a chamber body, and a first blocking piece and a liftable base assembly which are disposed in the chamber body, and the first blocking piece is fixedly connected to an inner wall of the chamber body, and is disposed along a circumferential direction of an inner wall of the chamber body; the base assembly includes a base body, a second blocking
10 piece, and a positioning structure, and the base body is coaxial with the chamber body and configured to bear a wafer; the second blocking piece is disposed on the base body along a circumferential direction of the base body, and when the base body is raised to a process position, the second blocking piece partially overlaps the first blocking piece, and a portion of the second blocking piece which overlaps the first
15 blocking piece is on a side of the first blocking piece away from the base body; and the positioning structure is disposed between the base body and the second blocking piece, and is configured to determine relative positions of the base body and the second blocking piece. The semiconductor chamber provided by the present disclosure can prevent the wafer from being covered and improve uniformity of a thin
20 film deposited on the wafer, thereby improving chip performance.

Fig. 2